

11060 U.S. PTO
12/18/01

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Atty. Docket No. AMAT/5813/ETCH/METAL/JB

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Box Patent Application
Assistant Commissioner of Patents and Trademarks
Washington, D.C. 20231

JC720 U.S. PTO
10/24/958
12/18/01

Re: Inventor(s): Melisa Buie; Brigitte Stoehr; and Guenther Ruhl
Title: ETCH PROCESS FOR PHOTOLITHOGRAPHIC RETICLE
MANUFACTURING WITH IMPROVED ETCH BIAS

Transmitted herewith is the patent application identified above, including:

Specification, claims and abstract, totaling 24 pages.
 Drawings totaling 3 pages, Formal Informal.
 Executed Declaration and Power of Attorney.
 Information Disclosure Statement w/ Form 1449 and References.
 Assignment of the invention to **Applied Materials, Inc.**
 Assignment Recordation Cover Sheet

FEE CALCULATION					
Fee Items	Claims Filed	Included With Basic Fee	Extra Claims	Fee Rate	Total
Total Claims	24	-20=	4	x \$18.00	\$72.00
Independent Claims	3	-3=	0	x \$84.00	\$84.00
Basic Filing Fee				\$740.00	\$740.00
TOTAL FEES					\$896.00

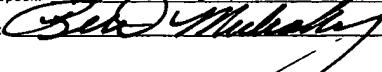
The Commissioner is hereby authorized to charge \$896.00 to Deposit Account No. 50-1074/AMAT/5813/ETCH/METAL/JB.
 The Commissioner is hereby authorized to charge any additional fees which may be required, or credit any overpayment to Deposit Account No. 50-1074/5813/ETCH/METAL/JB. A duplicate copy of this transmittal is enclosed.
 Please address all future correspondence to:

PATENT COUNSEL
APPLIED MATERIALS, INC.
Legal Affairs Department
P.O.BOX 450A
Santa Clara, CA. 95052

I hereby certify that this correspondence is being deposited with the United States Postal Service as express mail in an envelope addressed to: Commissioner for Patents, Box Patent Application, Washington, DC 20231.

Express Mail Receipt No.: EV 041916383 US

Date of Deposit: 12-18-01

Signature: 

Respectfully submitted,

Robert W. Mulcahy
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